

**Amendments to the Specification**

Please replace the paragraph beginning at page 17, line 25 with the following rewritten paragraph, which has been marked up to show changes made relative to the immediate prior version:

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C2

As shown, the susceptor 103 is suitably supported in the chamber 90 by the shaft 105. The shaft 105 is shown as being connected to the motor 104 to be rotated thereby and thus rotate the susceptor 103 and wafer 1 thereon about a generally vertical axis. Alternatively, in some wafer processing, the wafer and hence the shaft and susceptor need not be rotated, eliminating the need for the motor 104. The susceptor 103 is mounted to shaft 105 via arms 107, which, in the illustrated structure, extend radially from the shaft 105 and are angularly spaced. Although any number of arms 107 can be provided, three are used. The susceptor 103 is in spaced relation from the walls 91-96 and the door 97. The shaft 105 can be hollow to provide a pathway for thermocouple leads 110 for a thermocouple 111 ~~112~~ mounted relative to the susceptor 103 to provide temperature information. The susceptor ~~susceptor~~ 103 is located in an opening 112 in a floor 114 of the apparatus 88.

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